

# INFORMATION DISCLOSURE CITATION IN AN APPLICATION

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SERIAL NO.  
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APPLICANT  
**Xuelong SHI, et al.**

(PTO-1449)

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GROUP  
**2825**

## U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
<b>PEV</b>	5,229,872	7/20/1993	Mumola	<b>359</b>	<b>40</b>	
	5,242,770	9/7/1993	Chen et al.	<b>430</b>	<b>5</b>	
	5,296,891	3/22/1994	Vogt et al.	<b>355</b>	<b>67</b>	
	5,523,193	6/4/1996	Nelson	<b>430</b>	<b>311</b>	
	5,969,441	10/19/1999	Loopstra et al.	<b>310</b>	<b>12</b>	
	6,046,792	4/4/2000	Van Der Werf et al.	<b>355</b>	<b>53</b>	

## FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
<b>W</b>	WO 98/40791	9/17/1998	WIPO (PCT/IB98/00254) <b>ABSTRACT</b>			<input checked="" type="checkbox"/>	

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

<b>W</b>	E. Wolf, "Electromagnetic diffraction inoptical systems, I. An integral representation of the image field", Department of Theoretical Physics, University of Manchester, pp. 349-356, <b>dated 1959</b> .
	Michael S. Yeung et al., "Extension of the Hopkins theory of partially coherent imaging to include thin-film interference effects, SPIE Vol. 1927 Optical/Laser Microlithography VI (1993), pp. 452-463.
<b>W</b>	Donis G. Flagello et al., "Theory of high-NA imaging in homogeneous thin films", 1996 Optical Society of America, pp. 53-64.
	J. Fung Chen et al., "An OPC Technology Roadmap to 0.14 $\mu$ m Design Rules", SPIE Vol. 3236, pp. 382-396. <b>no date</b>
<b>W</b>	Robert Socha et al., "Forbidden Pitches for 130nm lithography and below", Proceedings of SPIE Vol. 4000 (2000), pp. 1140-4455.

EXAMINER **W. S. H.**

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